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Sheet 1 of 1

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INFORMATION DISCLOSURE STATEMENT
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Applicant

Alek C. CHEN

Filing Date

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Group

Not yet assigned

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U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Sub-Class	Filing Date (if appropriate)
ahn	5,327,221	07-1994	SAITOH et al	—	—	—
oh	5,373,232	12-1994	CRESSWELL et al	—	—	—
ah	5,585,211	12-1996	FIRSTEIN et al	—	—	—
oh	5,656,403	08-1997	SHIEH	—	—	—

FOREIGN PATENT DOCUMENTS

Document	Date	Country	Class	Sub-class	Translation Yes/No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

ahn	Scott HECTOR et al. "X-Ray Lithography for ≤ 100 nm Ground Rules In Complex Patterns," J. Vac. Society Technol. B, Vol 15, No 6, Nov/Dec. 1997, pp. 2517-2521

EXAMINER

Anadamarlin

DATE CONSIDERED

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